

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:	)	Confirmation No: 1187
Koichiro TANAKA et al.	)	Group Art Unit: 3742
Serial No. 10/579,238	)	Examiner: Sang Y. Paik
Filed: May 12, 2006	)	
For: LASER IRRADIATION APPARATUS	)	
AND LASER IRRADIATION METHOD	)	
	)	

**AMENDMENT**

Honorable Commissioner of Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

In response to the Official Action dated April 1, 2009, please consider the following amendments and remarks in connection with the above-identified application.

**Amendments to the Claims** are reflected in the listing of claims, which begins on page 2 of this paper.

**Remarks** begin on page 7 of this paper.